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RCE/1700
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ATTORNEY'S DOCKET: SAM435-100/00656

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Application No.: 09/614,785)
Filing Date: 07/12/00)
Applicants: CHO, DONG-IL)
For: SILICON ETCHING APPARATUS USING XeFe2)
Art Unit: ~~17636~~ 1763)
Examiner: HASSANZADEH, PARVIZ)

#5
7/18/02
MWREQUEST FOR CONTINUED EXAMINATION (RCE)

Director For Patents
Box: RCE
Washington, D.C. 20231

This is a Request for Continued Examination (RCE) under 37 CFR 1.114 of the above-identified application. Enclosed are the following:

1. SUBMISSIONS REQUIRED 37 CFR 1.114

- (a) ☐ Previously submitted
- i. ☐ Consider the amendment(s)/reply under 37 CFR 1.116 previous filed on _____.
- ii. ☐ Consider the arguments in the Appeal Brief or Reply Brief previously filed on _____.
- iii. ☐ Other _____.
- (b) ☒ Enclosed
- i. ☒ Amendment/Reply
- ii. ☐ Affidavit(s)/Declaration(s)
- iii. ☐ Information Disclosure Statement (IDS)
- iv. ☐ Other - Formal drawings as requested .

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2. MISCELLANEOUS

- (a) ☐ Suspension of action on the above-identified application is requested under 37 CFR 1.103(c) for a period of three months. (Period of suspension shall not exceed 3 months; Fee under 37 CFR 1.170(i) is required)
- (b) ☐ Other _____.

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3. **FEES** The RCE fee under 37 CFR 1.17(e) is required by 37 CFR 1.114 when filed.
- (a) X The director is hereby authorized to charge the following fees, or credit any overpayments, to Deposit Account 08-1500.
- i — RCE fee as required under 37 CFR 1.17(e)
- ii — Extension of time fee (37 CFR 1.136 and 1.17)
- iii X Other to charge any deficiencies in payment of fees to Deposit Account No. 08-1500.
- (b) X Check in the amount of \$370 is enclosed.
- (c) — Payment by credit card (Form PTO-2038 enclosed)

Respectfully Submitted

HEAD, JOHNSON & KACHIGIAN

Dated: 11 July 2002

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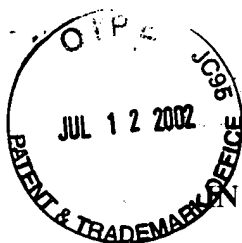
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Date of Deposit: 11 July 2002

I hereby certify that this paper or fee is being deposited with the United States Postal Service "Express Mail Post Office to Addressee" service under 37 CFR 1.10 on the date indicated above and is addressed to the United States Patent Office, Box RCE, Washington, DC 20231 by Amy Miles

Signature: Amy Miles



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AMENDMENT

Assistant Commissioner For Patents
Box: RCE
Washington, D.C. 20231

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Dear Sir:

The Applicant requests the above-identified application be re-opened in view of the following amendments:

In the Claims:

Delete claims 1 through 7 and add new claims 8 through 14 as follows:

- 1 8. (New) A method for etching a silicon wafer using XeF₂, comprising steps of:
- 2 (a) etching a silicon wafer using an etching apparatus comprising a loading chamber for
- 3 loading XeF₂, an expansion chamber for collecting sublimated XeF₂ from the said
- 4 loading chamber, and an etching chamber for etching using XeF₂ supplied from the
- 5 said expansion chamber; and
- 6 (b) eliminating air moisture in each chamber by injecting nitrogen to the loading
- 7 chamber, the expansion chamber or the etching chamber, and exhausting the injected
- 8 nitrogen therefrom prior to the said step (a).

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